List of Claims

Following is list of claims currently pending.

1. -9. (Cancelled)

10. (Previously Presented) A method for patterning structures on a substrate, comprising: providing a substrate underneath a tip of an Atomic Force Microscope;

providing a vapour of a material, which is suitable for Chemical Vapour Deposition onto the substrate when decomposed, in a space between the tip and the substrate; and

exposing the tip to a light beam emitted by a light emitting device in such a way that the tip intensifies an electromagnetic near-field to such an extent that the vapour is decomposed, wherein an intensity of the light beam is not enough to decompose the vapour.

- 11. (Original) A method according to claim 10, wherein providing said vapour comprises providing a gas selected from the group consisting of Halides, Hydrides, Metal Organic Compounds, AuClPF₃, W(CO)₆, TiCl₄, TaCl₅, WF₆, SiH₄, GeH₄, AlH₃(NMe₃)₂, NH₃, AlMe₃, Ti(CH₂tBu)₄, Ti(OiPr)₄, Ti(NMe₂)₄, Cu(acac)₂, and Ni(CO)₄.
- 12. (Original) A method according to claim 10, wherein exposing said tip to said light beam comprises emitting said light beam onto said tip in such a way that a polarization of said light beam is parallel to a longitudinal axis of said tip.

- 13. (Original) A method according to claim 10, further comprising adapting a wavelength of said light beam to match the size of said tip such that a sufficient amplification of said light beam is achieved.
- 14. (Original) A method according to claim 10, further comprising applying a laser to emit said light beam and exposing said tip to said light beam.
- 15. (Original) A method according to claim 10, wherein said Atomic Force Microscope has multiple tips, further comprising providing said substrate underneath said multiple tips.
- 16. (Original) A method according to claim 15, further comprising metalizing one or more of said multiple tips.